



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: Confirmation No. 1632

Norio KIMURA et al.

: Docket No. 2001-0660A

Serial No. 09/864,208

: Group Art Unit 1763

Filed May 25, 2001

: Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS  
AND SUBSTRATE POLISHING METHOD

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**ELECTION OF INVENTION**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action of January 8, 2004, applicants in the above-referenced application hereby elect the invention Group II corresponding to claims 16-37.

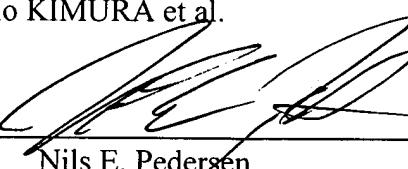
An early and favorable action on their merits is requested.

Respectfully submitted,

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
FEES FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

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By:



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